

## IN THE CLAIMS

1. - 35. (Cancelled)

36. (New) A method for producing an electron-emitting device, the device comprising a conductive film, opposite ends of which are connected respectively to electrodes and which includes an electron emission region therein between the electrodes, the method comprising the steps of:

ejecting through a droplet ejector a droplet containing a metal element toward a substrate, thereby supplying the droplet on the substrate, the metal element ejected in the ejecting forming the conductive film on the substrate;

detecting with a detector a position in the substrate where the droplet is to be supplied, prior to the supplying of the droplet, and detecting a state of the droplet supplied in the supplying; and

moving the droplet ejector according to the position detected by the detector, and controlling an ejecting condition of the droplet ejector on a basis of the state obtained via the detector.

37. (New) A method for producing an electron-emitting device, comprising the steps of:

ejecting through a droplet ejector a droplet onto a substrate, the droplet containing an ingredient for the electron-emitting device;

detecting with a detector a position in the substrate where the droplet is to be ejected, prior to the ejecting of the droplet, and detecting a state of the droplet ejected onto the substrate; and

moving the droplet ejector according to the position detected by the detector, and controlling an ejecting condition of the droplet ejector on a basis of the state obtained via the detector.